

# **3D Universal Optical Microscopes**

**Profilometer Series** 



Surface Roughness, Step Height, 3D Topography Cracks, Defects, Slope Measurement, Film Thickness, Sub Surface Feature



# **Impressive and Quick 3D Surface Profilometer**

#### **5 Imaging Modes in 1 Microscope**

Interferometry, Confocal, Dark Field, Bright Field, Variable Focus

The UP Series provides non-contact surface measurements from nano to micro and combines five imaging modes in one head to characterize all types of surfaces. One click causes the profilometer to switch between the different imaging modes automatically.

#### **Fast Scanning Speed**

High pixel colored images

The profiler comes with the latest generation cameras that allow scanning the surface with high speed. Our camera speed enables coverage of large areas and rapid stitching.

#### **Fully Automatic**

Automatic reporting, no need to be an expert

The sample surface is scanned with one click of a button, and an automatic test report in standard format is created with ease.

#### **User-Friendly Platform**

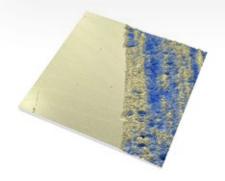
A cost-effective solution for your industry

The unique platform design comes with high-resolution encoders and open platform architecture. In addition, the cross roller XY stage allows for high precision measurements.



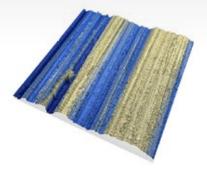
# 3D Profilometry Without Compromise For All Applications

Precise surface analysis in industry and research is essential to ensure optimal performance of materials and components



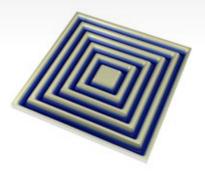
# Transparent Materials

- Glasses
- Wafers
- Contact lenses
- · Optics elements



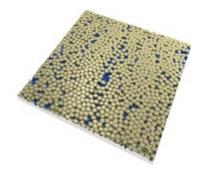
### Smooth and Rough Coatings

- Hard coatings
- Roughness
- Scratch analysis
- Porosity



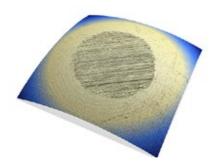
# Dark and Shiny Surfaces

- Mirror surface
- 3D waviness
- · Step height
- Crack analysis



#### **2D Materials**

- Film Thickness
- Grain size
- Defects
- Microstructure



#### Flat and Non-flat Surfaces

- Tooling
- Additive manufacturing
- Topography
- Volumes

## Bright. Dark. 3D

Universal Profilometer Unlike Any Other

## **Bright Field**

High speed and resolution

## **Dark Field**

Magnifies cracks and defects



# 5 Imaging Modes in 1 Microscope

3D Optical Surface Metrology

- White Light Interferometer (WLI)
  Highest Z resolution. A big plus for flat,
  nm height measurements.
- Confocal Microscopy Mode

  Highest lateral resolution. A big plus for transparent, translucent, steep slopes, multi-layer or rough samples
- Bright Field Mode
  Colored 2D images at high speed

- Dark Field Mode
  Highest contrast imaging. Detects cracks, defects, and failures with high resolutions not possible with any optical technique.
- Focus Variation

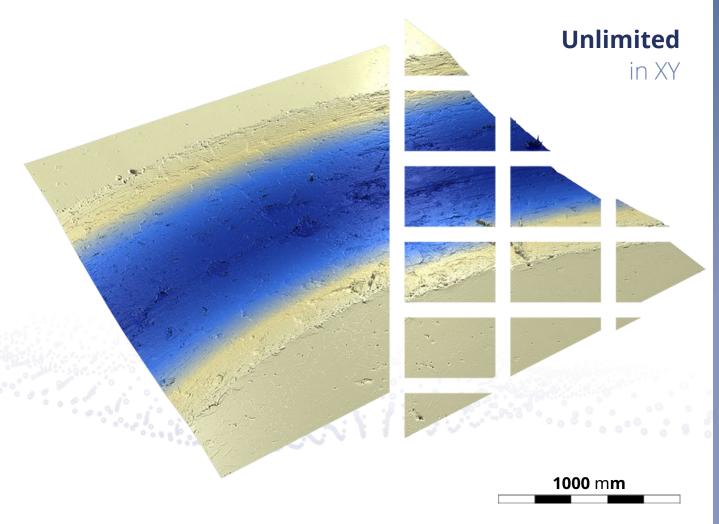
  Measures the shape and creates unifocus images of large areas at rapid speed.

## **Automatic Image Stitching**

The UP Series acquires a real color image without any sample movement.

Automatic image stitching is included in our software package, ensuring the acquisition of bigger images.

This mode offers the automated imaging of large surfaces at high magnifications.

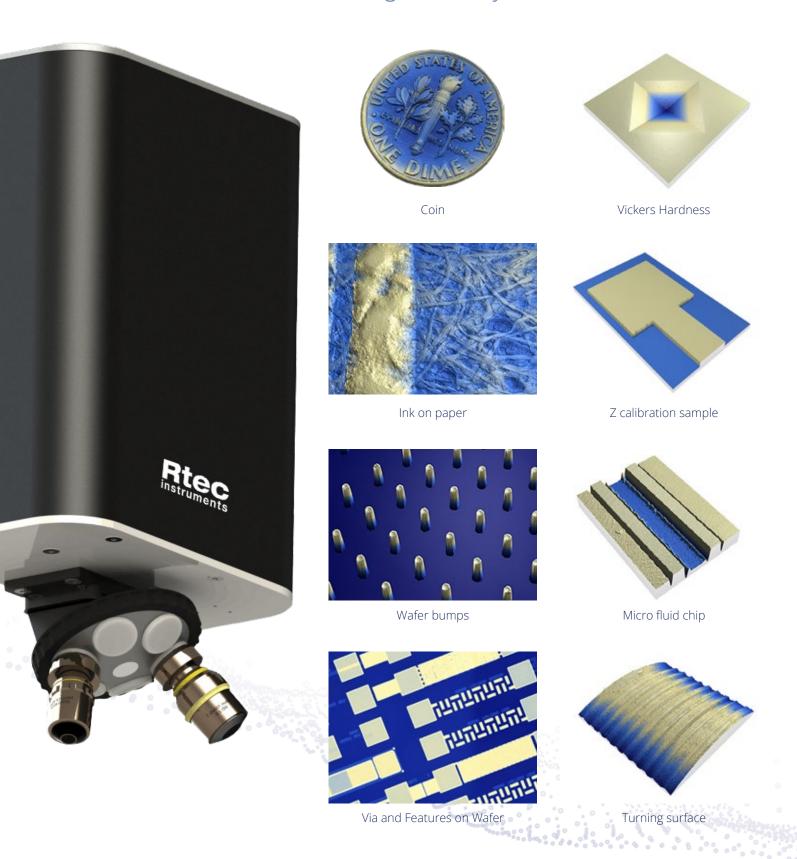


Available in

**All 5 Modes** 

## **3D Microscope For Multiple Applications**

The Most Powerful Package of Analysis On The Market



## **Confocal**

## Fastest area scanning confocal technique in the market

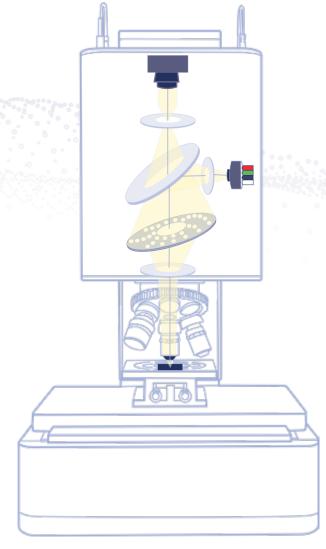
Nipkow Confocal Microscopy (Lambda Head) represents the best confocal technique.

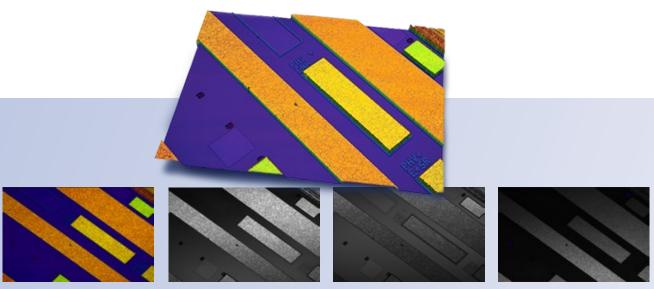
Rather than a single pinhole, the Lambda head has a thousand pinholes arranged on an opaque disk. These several simultaneously present pinholes that scan the sample and allow high-speed 3D image creation with nm resolution.

Our Lambda Confocal head offers the best in speed and resolution than any other confocal techniques such as point confocal to scan surface using XY stage or scanning XY mirrors to move the pinhole or using the pseudo digital confocal method.

#### **Key Features:**

- Our Confocal technique uses the highest NA objectives and optically produces the highest lateral resolution.
- Confocal microscopy can retrieve data from steep slopes, 72° vs. 44°, from interferometry.
- No limitation on surface roughness and surface reflectivity
- Colored images
- Find features on tough samples or transparent samples very easily.





## **Interferometry**

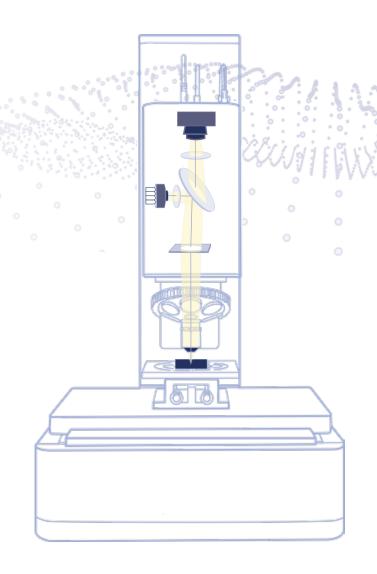
## Highest Z Resolution In Non-Contact Profilometry

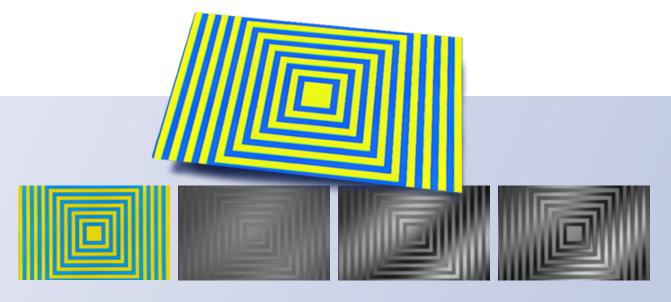
White light interferometry (WLI) is an optical surface topography measurement technique that uses scanning interferometry to generate 2D and 3D models of surface height.

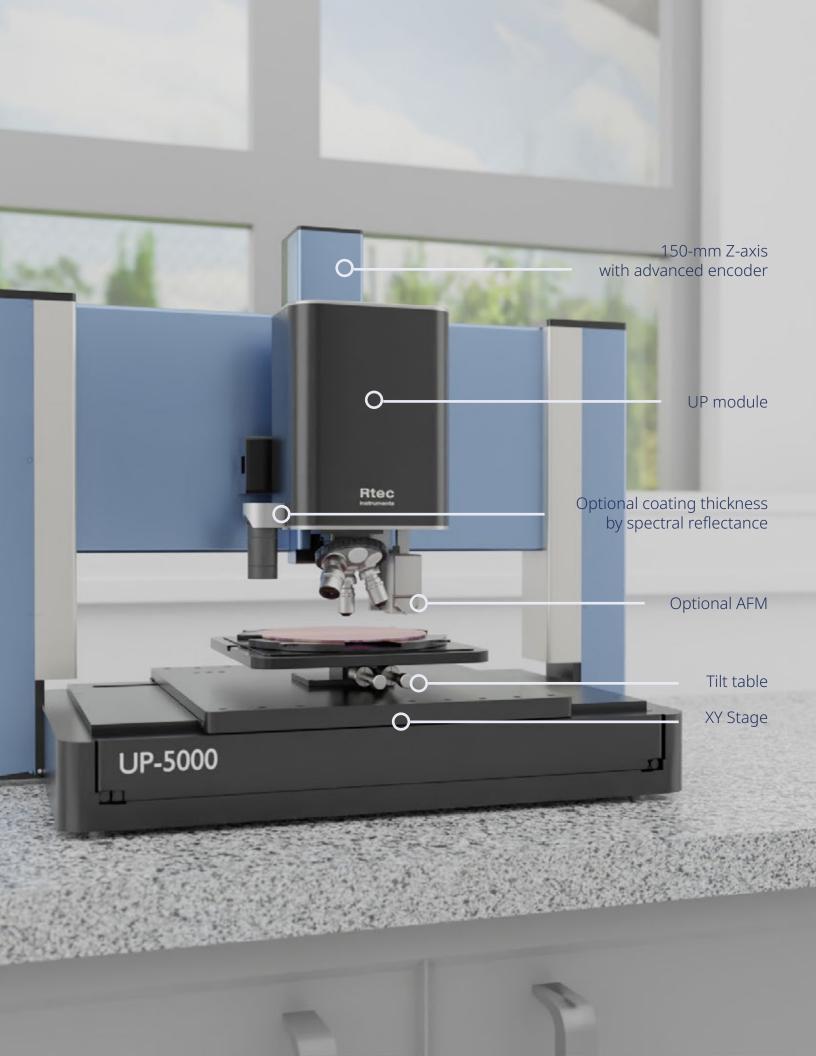
Light reflects from the reference mirror, and the sample is recombined at the beam splitter to create interferograms.

#### **Key Features:**

- One of the fastest cameras (250 FPS+) used for WLI in the market
- Highest Z resolution, sub-nanometer
- · Z resolution independent of magnification
- User-selectable four-color LED light source (white, red-630nm, green-530nm, and blue-460nm) improves lateral resolution and optical coherence length (blue light provides higher lateral resolution)







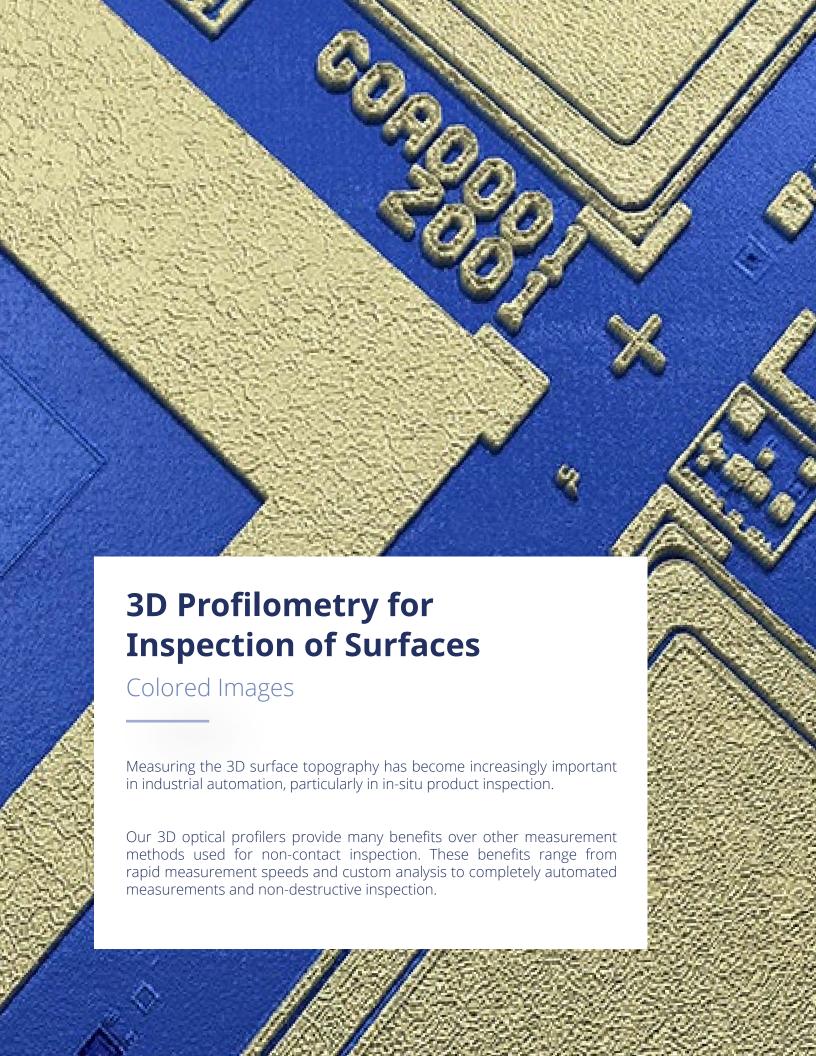
## **Platforms**

## Profilometer Series



	UP-5000	UP-3000	UP-2000
Bright and Dark Field	✓	✓	
Spinning Disk Confocal	✓	✓	
White Light Interferometry	✓	✓	✓
Variable Focus Imaging	✓	✓	
3D Image Stitching	$\checkmark$	✓	✓
Spectral Reflectance Profilometry	✓		
AFM	✓		
Raman Microscope	✓		
XYZ Stage*	300 x 300 x 150 mm	150 x 200 x 150 mm	150 x 200 x 150 mm

<sup>\*</sup> more custom options are available



## **Software**



# **Analysis Package and International Standards**

The UP modules series come with several test-specific standards for data traceability and quick platform checkup. The instruments also come with standard test recipes to ensure normalized testing.

- Real time imaging of 3D surface topography.
- Overlay color and intensity images on 3D topography.
- Data acquisition artifact processing outliers, local defects.
- Roughness and surface texture with the latest ISO and national standards.
- Extraction and analysis regions of interest (Page viewer for fast navigation.)
- Modules for advanced surface texture analysis, contour analysis, grains, and particles analysis, 3D Fourier analysis, image co-localization, statistics, and more.
- Fast, automated, traceable surface analysis report creation
- Pass/fail criteria with green/red traffic lights can be specified for any parameter.
- Series of measurements can be analyzed automatically using templates and minidocs (common sequences of analysis steps).



## **Specifications**

## **Interferometry Objectives**

	2.5X	5X	10X	20X	50X	100X	
Numerical Aperture (NA)	0.075	0.13	0.3	0.4	0.55	0.7	
Working Distance (mm)	10.3	9.3	7.4	4.7	3.4	2.0	
FOV (um)	6910 x 5180	3460 x 2590	1730 x 1300	860 x 650	350 x 260	170 x 130	
Optical Resolution (L&S 460 nm) (um)	1.87	1.08	0.47	0.35	0.26	0.20	
Vertical Resolution	Better than 0.01nm						
Vertical RMS repeatability RMS	0.01nm						

## Confocal, Bright Field, and Dark Field Objectives

	Standard Working Distance				Long Working Distance				
	5X	10X	20X	50X	100X	150X	20X	50X	100X
Numerical Aperture (NA)	0.15	0.3	0.45	0.8	0.9	0.95	0.4	0.6	0.8
Working Distance (mm)	23.5	17.5	4.5	1.0	1.0	0.3	19	11	4.5
Field of view (um)	3460 x 2590	1730 x 1300	860 x 650	350 x 260	170 x 130	120 x 90	860 x 650	350 x 260	170 x 130
Optical Resolution (L&S 460nm)(um)**	0.94	0.47	0.31	0.18	0.16	0.15	0.35	0.23	0.18
Vertical Resolution (nm)	72.0	18.0	8.0	2.5	2.0	1.8	10.1	4.5	2.5





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